# Special Issue

## MEMS/NEMS Devices and Applications, 3rd Edition

### Message from the Guest Editors

Recently, nanoelectromechanical system (NEMS) and microelectromechanical system (MEMS) technologies have been employed to develop various microdevices and microstructures. Many sensors and actuators have been manufactured and commercialized using technologies such as pressure sensors, accelerometers, gyroscopes, tactile sensors, thermal sensors, flow sensors, optical sensors, image sensors, microphones, magnetic sensors, chemical sensors, gas sensors, biosensors, microchannels, ink jet heads, optical switches, RF switches, micromirror, motors, relays, resonators, filters, and energy harvesters. NEMS/MEMS devices have been widely applied in various fields. This Special Issue requests outstanding research on NEMS/MEMS devices and applications. Submissions related to the novel designs, fabrication, development, and applications of various NEMS/MEMS devices, including physical sensors, chemical sensors, gas sensors, biosensors, actuators, energy harvesters, etc., based on NEMS/MEMS technologies are welcome. Review articles and original research articles are equally welcome.

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### Deadline for manuscript submissions

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## Editor-in-Chief

Prof. Dr. Ai-Qun Liu
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